

PATENT



Attorney Docket No.: A-68359-1 (475852-7)

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re application of:

Gerard S. MOLONEY

Serial No. 10/027,935

Filed: December 21, 2001

For: APPARATUS AND METHOD  
FOR CHEMICAL-MECHANICAL  
POLISHING (CMP) HEAD  
HAVING DIRECT PNEUMATIC  
WAFER POLISHING PRESSURE

Group Art Unit: 3724

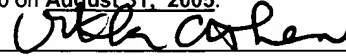
Examiner: ELEY, Timothy V.

Confirmation No.: 2631

**CERTIFICATE OF MAILING**

I hereby certify that this correspondence and its listed  
enclosures is being deposited with the United States  
Postal Service as First Class Mail addressed to  
Commissioner for Patents; P.O. Box 1450; Alexandria, VA  
22313-1450 on August 31, 2005.

Signed

  
Vikki Athen

**CHANGE OF CORRESPONDENCE ADDRESS**

BOX AF

Commissioner for Patents

P. O. Box 1450

Alexandria, Virginia 22313-1450

Please change the correspondence address for the above-identified patent application to the  
address indicated below, and address all correspondence to R. Michael Ananian at:

DORSEY & WHITNEY LLP  
Intellectual Property Department  
555 California Street, Suite 1000  
San Francisco, CA 94104-1513

Respectfully submitted,

DORSEY & WHITNEY LLP

By: 

R. Michael Ananian, Reg. No. 35,050

Dated: 8/31/2005

Customer Number: 32940  
DORSEY & WHITNEY LLP  
Intellectual Property Department  
555 California Street, Suite 1000  
San Francisco, CA 94104-1513  
Telephone: (415) 781-1989  
Facsimile: (415) 398-3249